Meeting for announcing results of FineMEMS Project

(1) Purpose
This conference is held to disclose the interim achievements of the “Highly Integrated and Complex MEMS Manufacturing Technology Development Project,” a three-year project that has been implemented since FY 2006 by NEDO. This project, also known as the “Fine MEMS” project, seeks to develop key manufacturing technologies for the creation of complex and integrated functions through the creation of advanced tiny three-dimensional structure processing technologies and the use of nanomaterials and different types of materials. This is a key technology supporting the development of the MEMS industry.

(2) Program
Highly Integrated and Complex MEMS Manufacturing Technology Development Project (FY 2006 - 2008) (commissioned by / subsidy provided by NEDO)

Meeting for announcing results of FineMEMS Project

Date & Time: July 31, 2008 (Thursday) 12:30 - 4:30 p.m.
Venue: Tokyo Big Sight (Tokyo International Exhibition Center, West Hall 1)
19th Exhibition Micromachine/MEMS special venue
Sponsor: New Energy and Industrial Technology Development Organization (NEDO) / Micromachine Center
Support: Ministry of Economy, Trade and Industry (planned)
Attendance: Free of charge but first-come-first-serve due to limited seating capacity (200) and quantity of extended abstracts

Micro / Nano 2008 MEMS Forum

(1) Purpose
The MEMS Forum is a forum for the exchange of information and views regarding the various activities of the MEMS Industry Forum. Its purpose is to achieve a deeper common recognition of the issues that must be resolved for the expansion and development of MEMS-related industries. The Forum introduces the status of activities by the MEMS Industry Forum and affiliate members (local clusters, publicly funded laboratories and academia), from the perspective of building an infrastructure for the MEMS industry and the creation and development of a MEMS technical infrastructure through industry-academic collaboration.

(2) Program

Micro / Nano 2008 MEMS Forum – For the Development of MEMS Industries –

Date & Time: August 1, 2008 (Friday) 10:30 a.m. - 4:35 p.m.
Venue: Tokyo Big Sight (Tokyo International Exhibition Center, West Hall 1)
19th Exhibition Micromachine/MEMS special venue
Sponsor: MEMS Industry Forum / Micromachine Center
Attendance: Free

Opening Remarks
Chair: Tomoyuki Koike, Micromachine Center

Session 1
Opening Remarks
10:30 - 10:35
Koichi Imanaka, Assistant Director, MEMS Industry Forum

Overview of MEMS Industry Forum activities
10:35 - 10:50
Keiichi Aoyagi, Micromachine Center

Strengthening of MEMS industry infrastructure
10:50 - 11:05
Isao Shimoyama, The University of Tokyo

Break
11:05 - 11:20

Technical strategy roadmap for the MEMS field
11:20 - 11:30
Hideaki Watanabe, NEDO

Introduction to the Micro Energy Research Council, Micro/Nano Optical Specialist Forum, Japan Society of Mechanical Engineers
11:30 - 11:40
Hiroyuki Kuwano, Tohoku University

Opening Remarks
Chair: Shun'ichi Adegawa, Micromachine Center

Session 2
Industry-Academic Collaboration Session
Organizer: Professor Kazuo Sato, Nagoya University

Issues for MEMS Industry Development
14:30 - 14:35
Kazuo Sato, Nagoya University

AIST training of micro/nano manufacturing personnel, focusing on industry-academic personnel training partnership projects
14:35 - 14:50
Professor Kunie Okada, Tokyo University

Introduction to the Micro Energy Research Council, Micro/Nano Optical Specialist Forum, Japan Society of Mechanical Engineers
14:40 - 14:50
Hiroki Kuwano, Tohoku University

MEMS – semiconductor transverse wiring technologies (high-density low temperature laminate integration mounting technologies)
14:40 - 14:50
Jun Akedo, AIST

Overview of Fine MEMS Project
14:50 - 15:05
Toshio Sakamizu, Micromachine Center

Break
15:05 - 15:20

Introduction of MEMS industry strategies and expectations for the Fine MEMS Project
15:20 - 15:35
Makoto Korenaga, Ministry of Economy, Trade and Industry

Break
15:35 - 15:50

International Standardization Trends in MEMS Fields
15:50 - 16:05
Professor Kunie Okada, Tokyo University

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Case studies of the use of MEMS technologies in research and development assistance by the Kanagawa Industrial Technology Center
16:10 - 16:15
Manabu Yasui, Kanagawa Industrial Technology Center

MemsONE functions and future plans (MEMS design and analysis support system) Ver. 1.1
16:15 - 16:30
Takahisa Maeda, MemsONE Consortium, Nihon Unisys Excleutions

Closing
16:30 - 16:35
Keiichi Aoyagi, Micromachine Center